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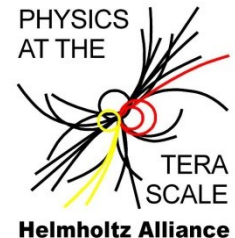
Analysis of TCT measurements of highly irradiated silicon pad diodes under forward bias

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Erika Garutti, Robert Klanner, Christian Scharf
Institut für Experimentalphysik
Universität Hamburg





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Analysis of TCT measurements of highly irradiated silicon photodiodes under forward

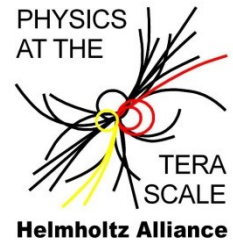
Preliminary

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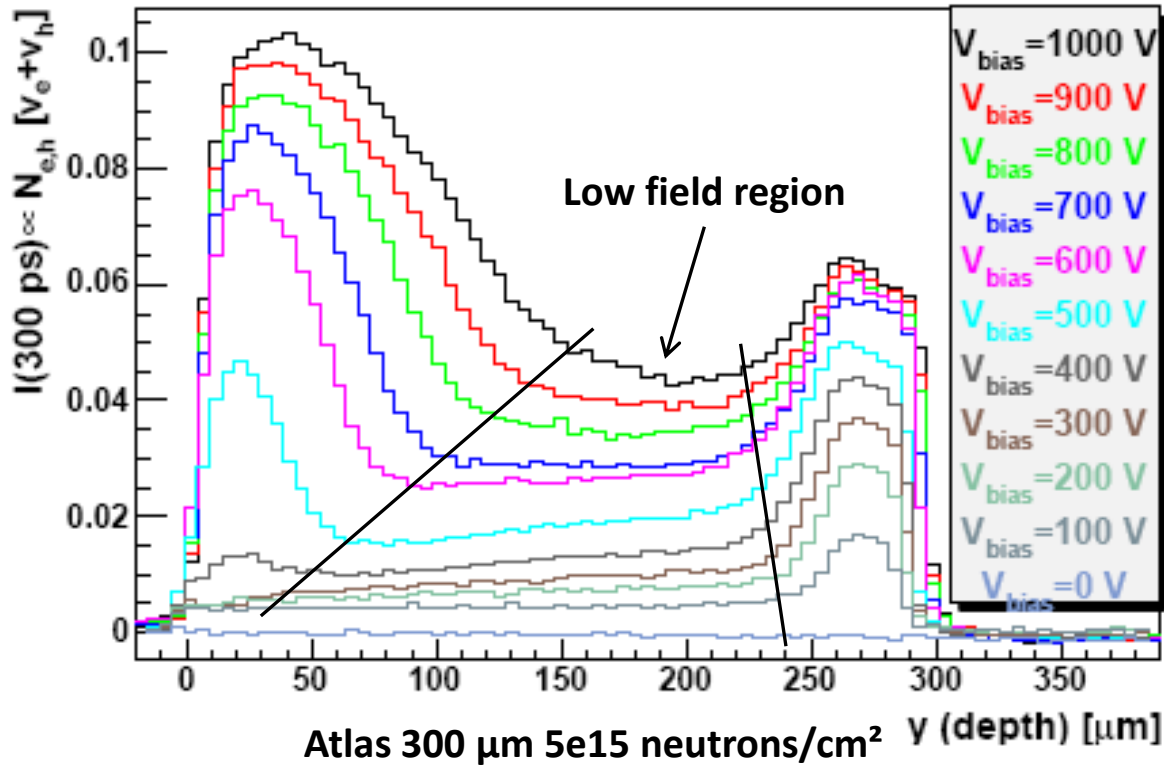


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Motivation

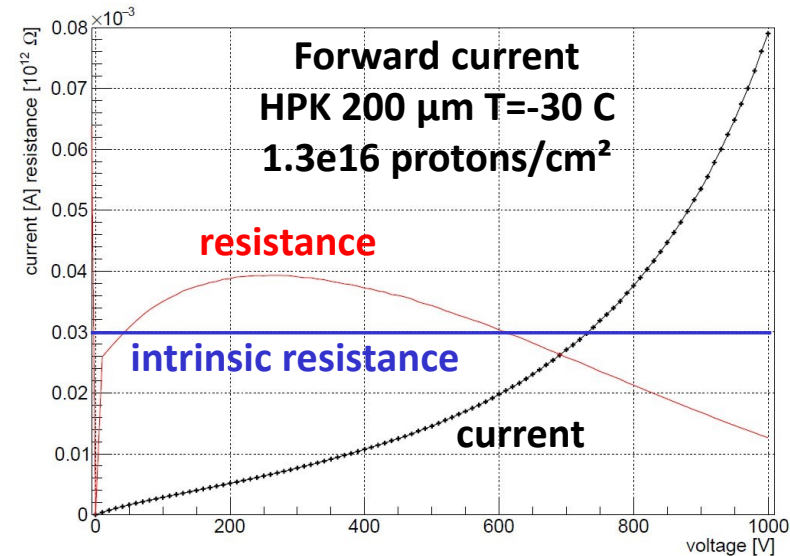
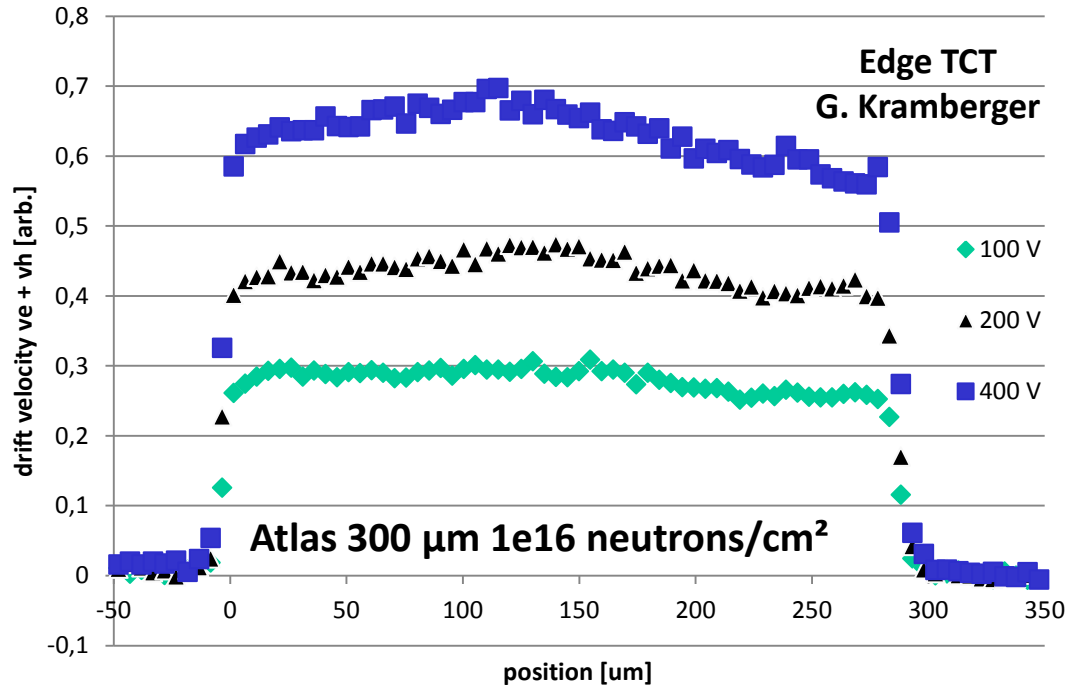


Edge TCT
 G. Kramerberger
 Vertex 2010

Let's have a look at reverse biased highly irradiated sensors:

- „Double junction“ with high field near contacts
- Moderate E-field and low trapping in between
- Many unknown parameters: $v_{e,h}(x)$, $\tau_{e,h}(x)$, $E(x)$

Motivation



Forward bias makes life easy: $v_{e,h} = const \rightarrow$ electric field $E = const$

Similar to low field region for reverse bias

- Carrier densities $n_e \approx n_h \rightarrow$ behaves like a resistor (intrinsic material)
- Constant trap occupation $\rightarrow \tau_{e,h} = const$



Experimental method

Transient Current Technique

- Pulsed laser generates e-h pairs
- Charge carriers drift in E-field
 $\rightarrow I \propto v_d(E) \cdot \exp(-t/\tau)$

Sensors: Float-zone and MCZ silicon n- and p-bulk **pad diodes**

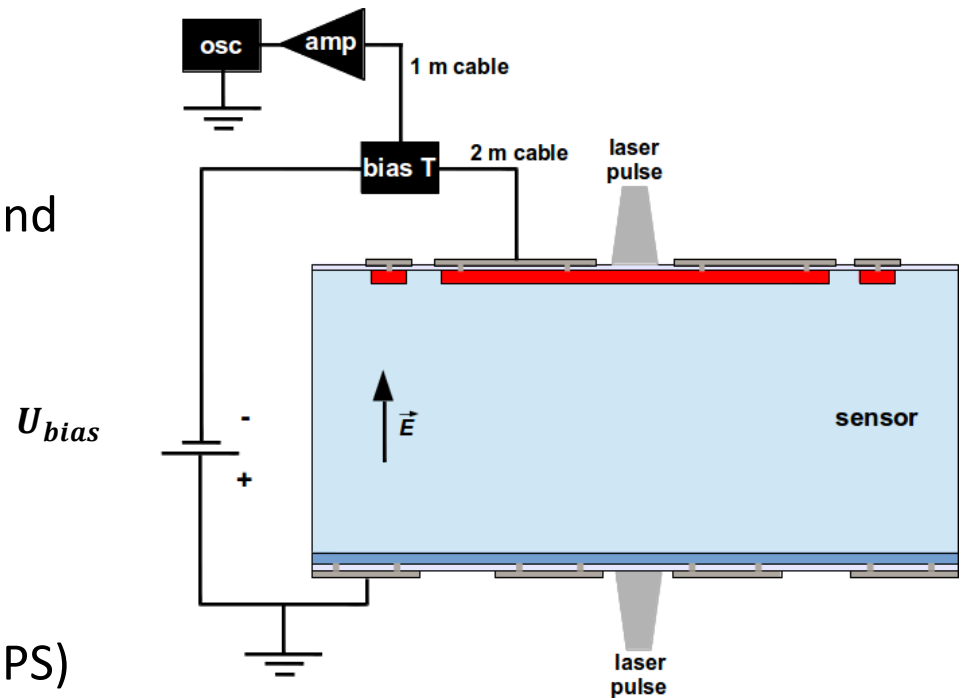
Measurements

Reference non irradiated

- 400 V – 500 V

Irradiated

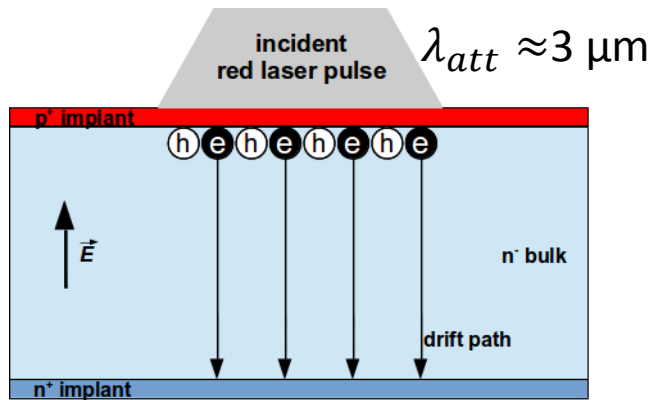
- Fluence $1e15 - 1.3e16$ protons/cm² (PS)
- $-1000 \text{ V} < U_{bias} \leq 1000 \text{ V}$ @ -30 C



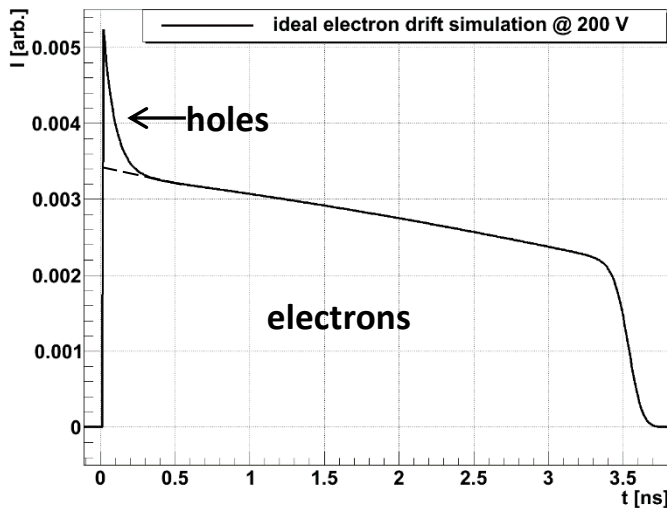
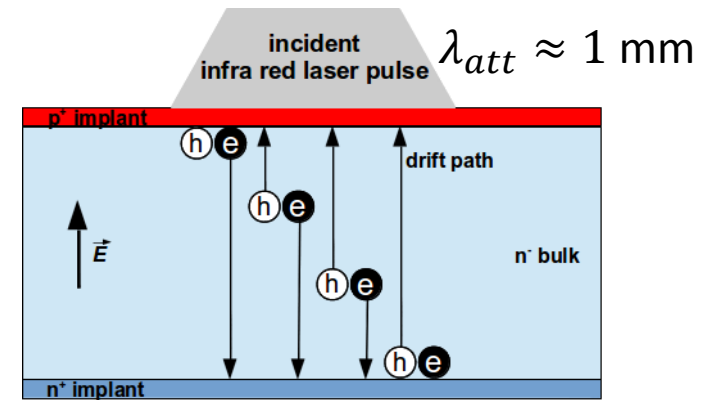
Transient Current Technique

- **Red laser 675 nm**
 → signal induced by drift of **e or h**

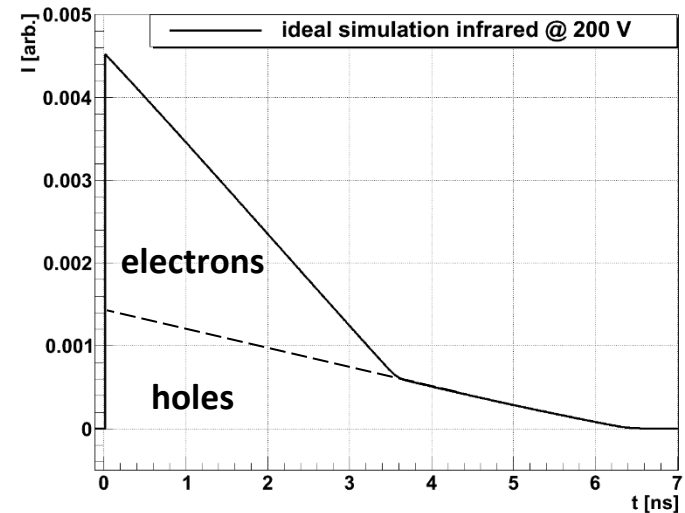
- **Infrared laser 1063 nm**
 → simultaneous **e and h** drift



initial charge distribution



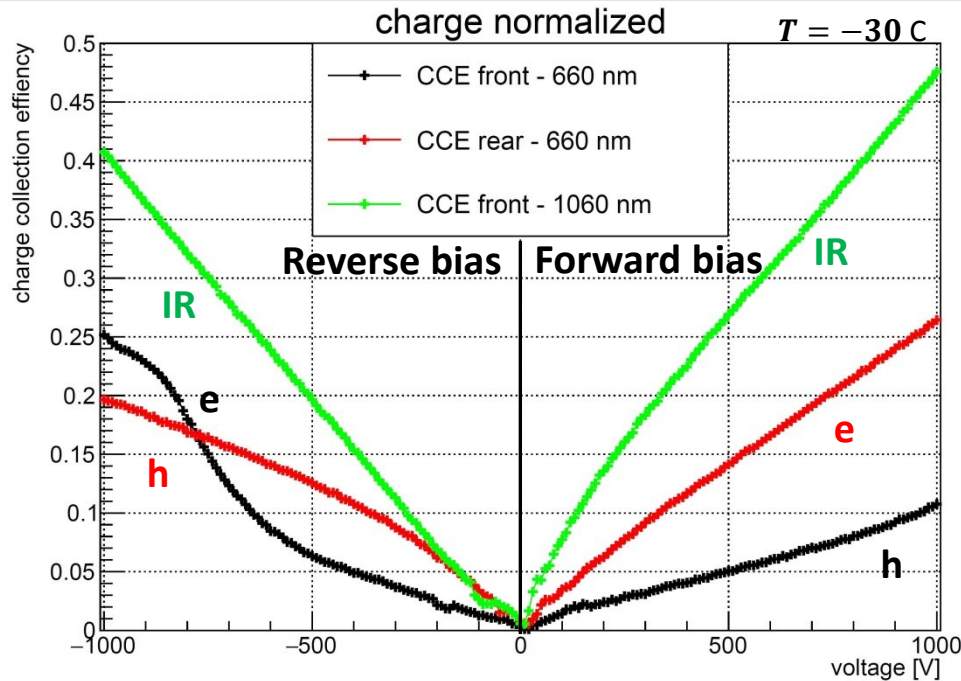
drift simulation
200 μm sensor
@ 200 V





First results

The charge collection length



HPK p+n pad sensor
 Thickness $w = 200 \mu\text{m}$
 1.3×10^{16} protons/cm²

$$E(x), v_{e,h} \text{ and } \tau_{e,h} = \text{const}$$

→ Determine charge collection length $\lambda_{e,h} = v_{e,h} \cdot \tau_{e,h}$ for red laser:

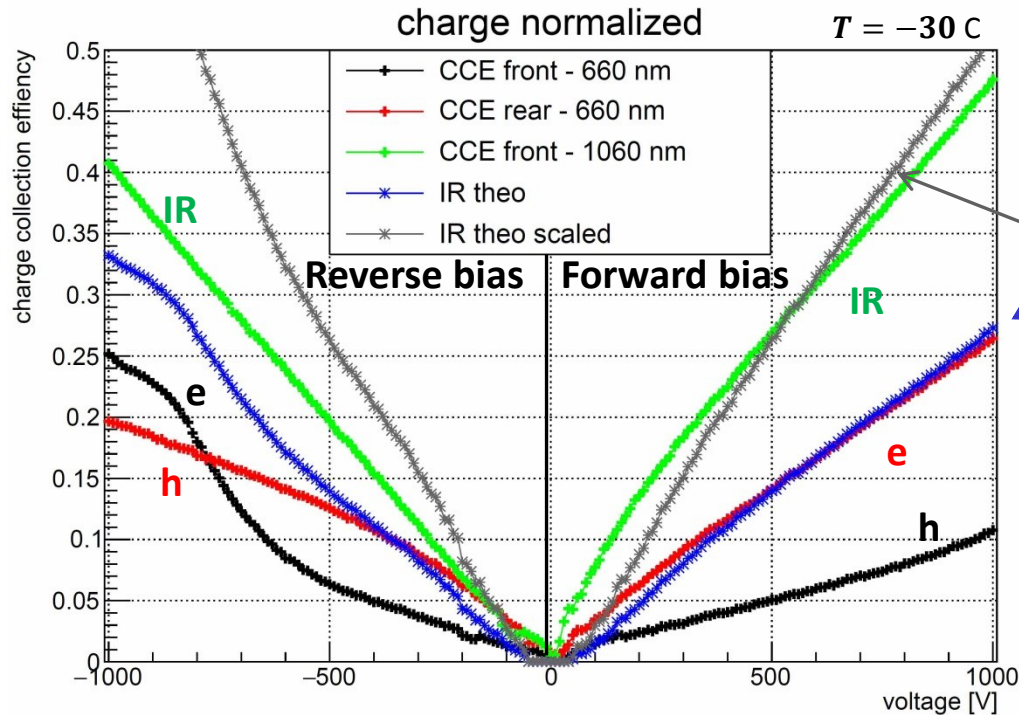
$$Q_{red} \approx Q_{dep} \left[\frac{w - \lambda_{att}}{w} \cdot \frac{\lambda_{e,h}}{w} \left(1 - e^{-\frac{w}{\lambda_{e,h}}} \right) + \lambda_{att}/w \right]$$

Q_{dep} : Deposited charge
 λ_{att} : Attenuation length

Charge drifting through the sensor

Charge collected at illuminated electrode ($\lambda_{att} \ll \lambda$)

CCE for infrared laser



Q_{IR} calculated from $\lambda_{e,h}$ with
 $Q_{dep,IR} = 1.9 \cdot Q_{ref,IR}$
 $Q_{dep,IR} = Q_{ref,IR}$ for both cases
 $Q_{dep,red} = Q_{ref,red}$

200 μm HPK p+n
 1.3×10^{16} p/cm²

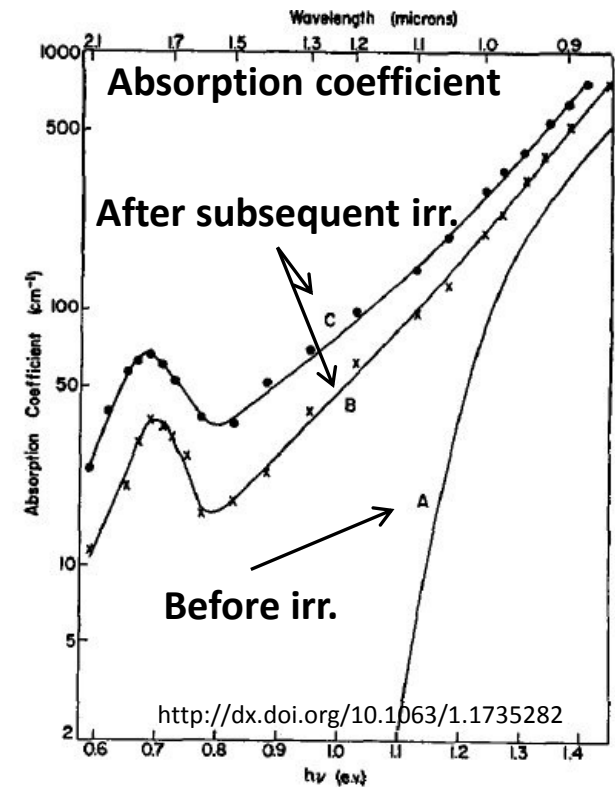
Now we know $\lambda_{e,h} \rightarrow$ Determine CCE for infrared laser ($\lambda_{att} \rightarrow \infty$):

$$Q_{IR} \approx Q_{dep,IR} \left(\frac{\lambda_e}{w} \left(1 - \frac{\lambda_e}{w} \left(1 - e^{-\frac{w}{\lambda_e}} \right) \right) + \frac{\lambda_h}{w} \left(1 - \frac{\lambda_h}{w} \left(1 - e^{-\frac{w}{\lambda_h}} \right) \right) \right)$$

Fair approximation for $Q_{dep,IR} = 1.9 \cdot Q_{ref,IR} \rightarrow$ Does the light absorption change?

Indeed: Absorption coefficient changes with irradiation also for low wavelength

- Excitation of defect levels
- Bare silicon pieces, diodes, and strip sensors at PS for proton irradiation
 - Measure **absorption for relevant fluences and wavelengths**
 - Measure absorption with bias voltage
 - Filling of traps
 - FTIR defect spectroscopy possible

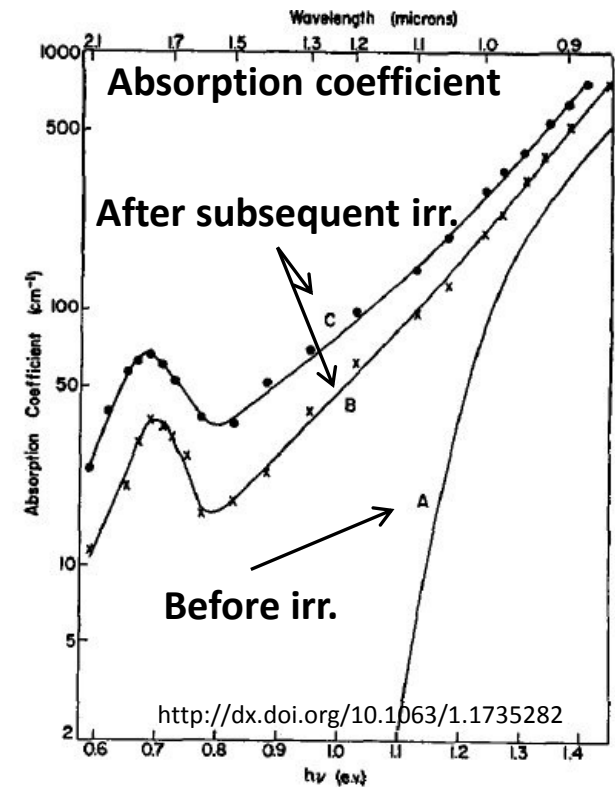


Indeed: Absorption coefficient changes with irradiation also for low wavelength

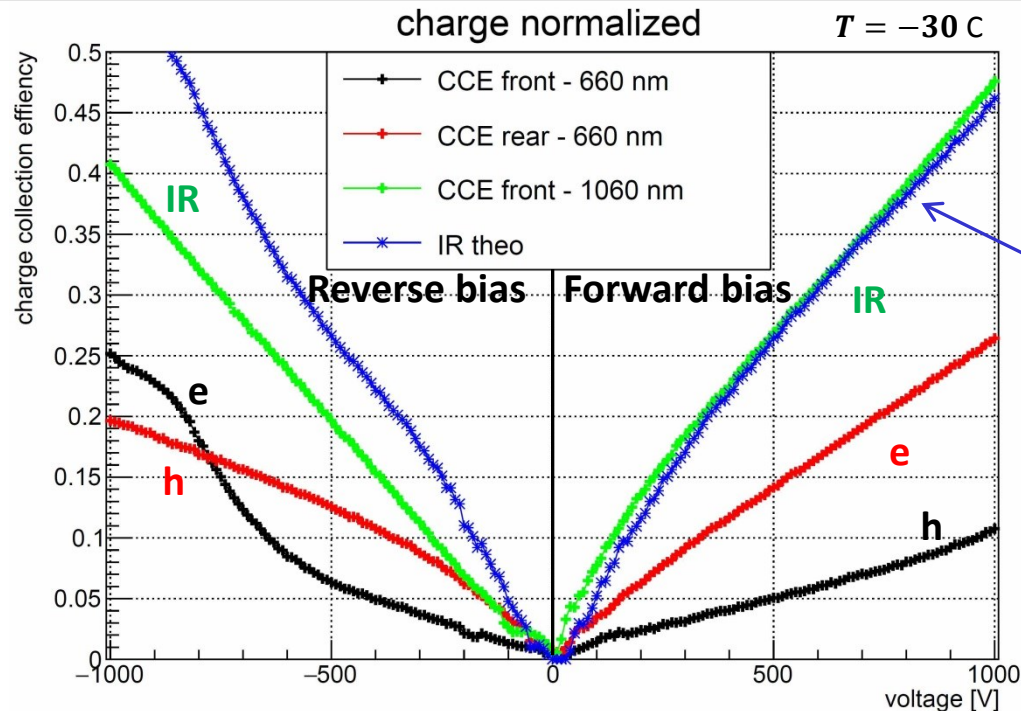
- Excitation of defect levels
- Bare silicon pieces, diodes, and strip sensors at PS for proton irradiation
 - Measure **absorption for relevant fluences and wavelengths**
 - Measure absorption with bias voltage
 - Filling of traps
 - FTIR defect spectroscopy possible

Next steps:

- **Check** $Q_{dep,red} = \frac{Q_{ref,red}}{1.9}$
- **Assume** $Q_{dep,IR} = 1.9 \cdot Q_{ref,IR}$ **and** $Q_{dep,red} = Q_{ref,red}$
- **Disentangle drift velocity and trapping**
- $I(t) \propto q \cdot v \cdot e^{-vt/\lambda}$
 - Fit the drift velocity v to transients
 - Extract $\tau_{e,h}$



CCE for infrared laser



Q_{IR} calculated from $\lambda_{e,h}$ with

$$Q_{dep,IR} = Q_{ref,IR}$$

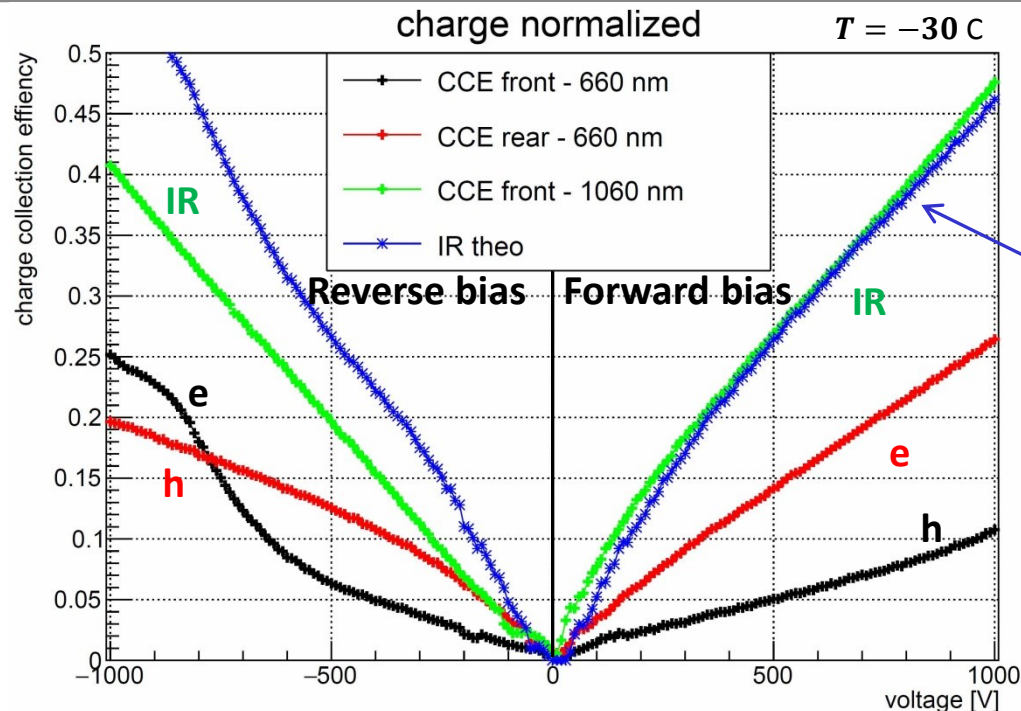
$$Q_{dep,red} = \frac{Q_{ref,red}}{1.9}$$

200 μm HPK p+n
 1.3×10^{16} p/cm²

Increase absorption for red laser \rightarrow Obtained values of $\lambda_{e,h}$ larger

- Better approximation of CCE for $Q_{dep,red} = \frac{Q_{ref,red}}{1.9}$
- **We need to know λ_{att}** as function of wavelength and fluence
- And use correct term for CCE:

CCE for infrared laser



Q_{IR} calculated from $\lambda_{e,h}$ with

$$Q_{dep,IR} = Q_{ref,IR}$$

$$Q_{dep,red} = \frac{Q_{ref,red}}{1.9}$$

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Increase absorption for red laser \rightarrow Obtained values of $\lambda_{e,h}$ larger

- Better approximation of CCE for $Q_{dep,red} = \frac{Q_{ref,red}}{1.9}$

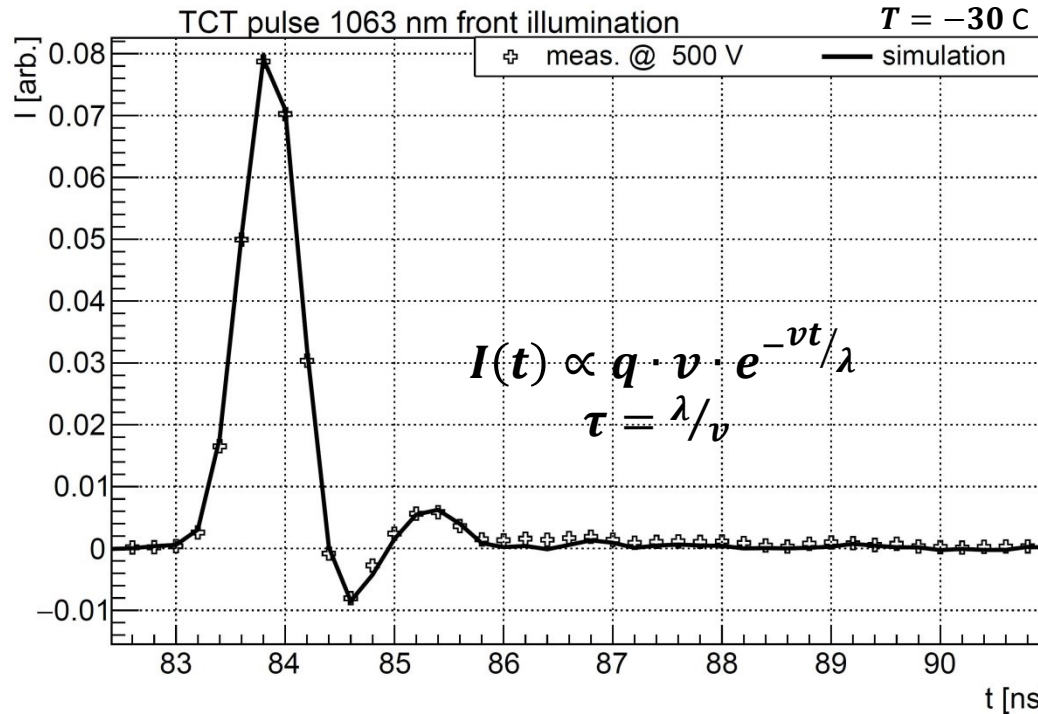
- **We need to know λ_{att}** as function

- And use correct term for CCE:

$$\frac{\lambda_e \lambda_\gamma \left(\left(1 - e^{-\frac{d}{\lambda_e}} \right) \lambda_e + \left(-1 + e^{-\frac{d}{\lambda_\gamma}} \right) \lambda_\gamma \right)}{\lambda_e - \lambda_\gamma} + \lambda_h \lambda_\gamma \left(1 - e^{-\frac{d}{\lambda_\gamma}} + \frac{\left(-1 + e^{-d \left(\frac{1}{\lambda_h} + \frac{1}{\lambda_\gamma} \right)} \right) \lambda_h}{\lambda_h + \lambda_\gamma} \right)$$

$$d \left(1 - e^{-\frac{d}{\lambda_\gamma}} \right) \lambda_\gamma$$

Drift velocity and trapping



200 μm HPK p+n
 1.3e16 GeV p/cm²

Infrared illumination
@ 500 V forward

Normalized with
 $Q_{dep,IR} = 1.9 \cdot Q_{ref,IR}$

Simulation fits nicely (here $E = 25\text{ kV/cm}$)

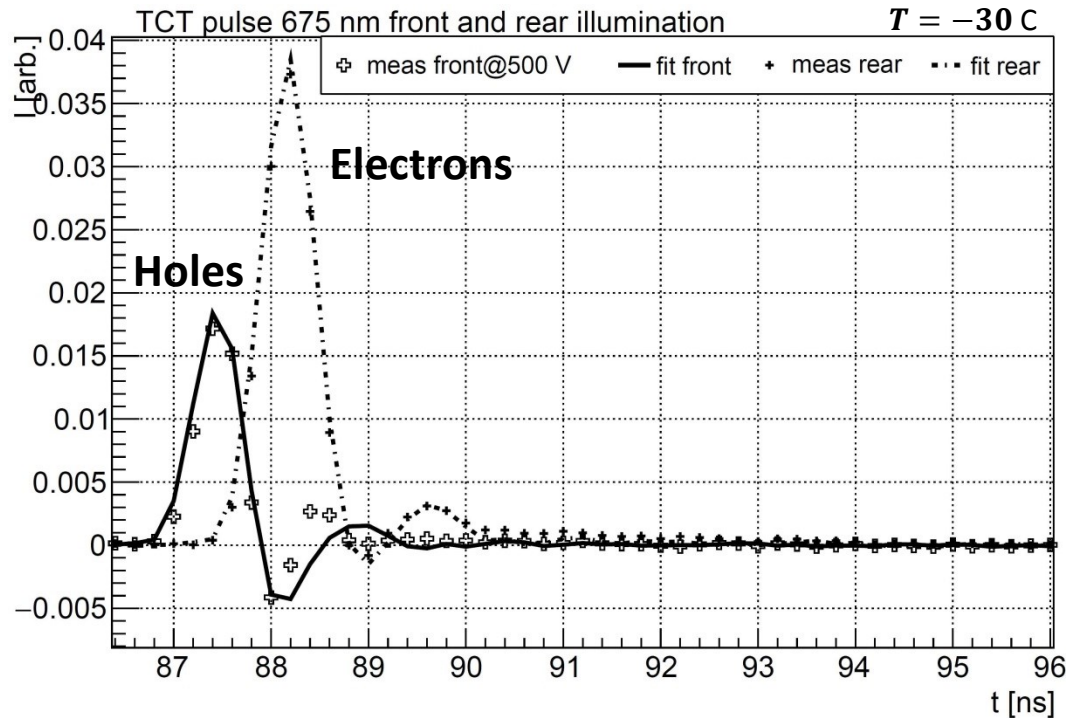
- v reduced by 35 % \rightarrow compare $\sim 10^{16}$ /cm³ ionized impurities
- **Very low trapping for 1.3e16 GeV p/cm²:**
 - $\tau_e = 400\text{ ps}$
 - $\tau_h = 140\text{ ps}$

„Safety margin“

$$Q_{dep,red} = \frac{Q_{ref,red}}{1.9}$$

- v increased by 20 %
 \rightarrow unphysical
 - $\tau_e = 460\text{ ps}$
 - $\tau_h = 180\text{ ps}$

Transients for the red laser



200 μm HPK p+n
 1.3×10^{16} GeV p/cm^2

**Red laser illumination
 @ 500 V forward**

Normalized with
 $Q_{dep} = Q_{ref,red}$

- Electron drift is nicely described
- Hole drift is not well described
 - Transfer function not accurate enough \longrightarrow

To be continued
 More samples!



Conclusion and outlook

- **New method to determine the drift velocity and trapping in forward bias established**
 - Determine charge collection length λ from CCE
 - Fit drift velocity to transients $I(t) \propto q \cdot v \cdot e^{-vt/\lambda}$
 - Calculate $\tau(E) = \lambda/v$
 - **Absorption length of light changes** with irradiation
 - **Reduction of the drift velocity?**
 - **Very high lifetimes of electrons and holes**
 - **Agenda:**
 - Measure light absorption in irradiated silicon $\rightarrow Q_{dep}$ for IR and red laser
 - Determine $v(E)$ and $\tau(E)$ systematically for different fluence + bias + material
- \rightarrow Apply results for the low field region to better understand reverse bias**



Thanks for your attention

Special thanks to
J. Becker, E. Fretwurst , R. Klanner

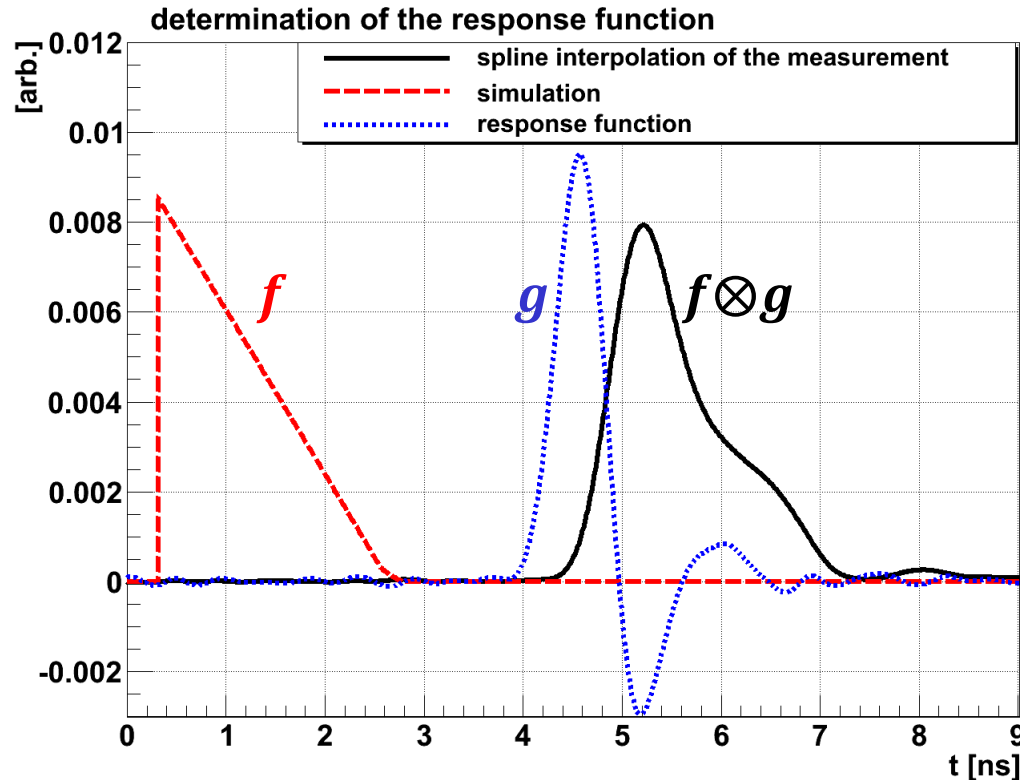


Backup

Electronics transfer function

Convolution theorem:

$$\mathcal{F}\{f \otimes g\} = \mathcal{F}\{f\} \cdot \mathcal{F}\{g\}$$

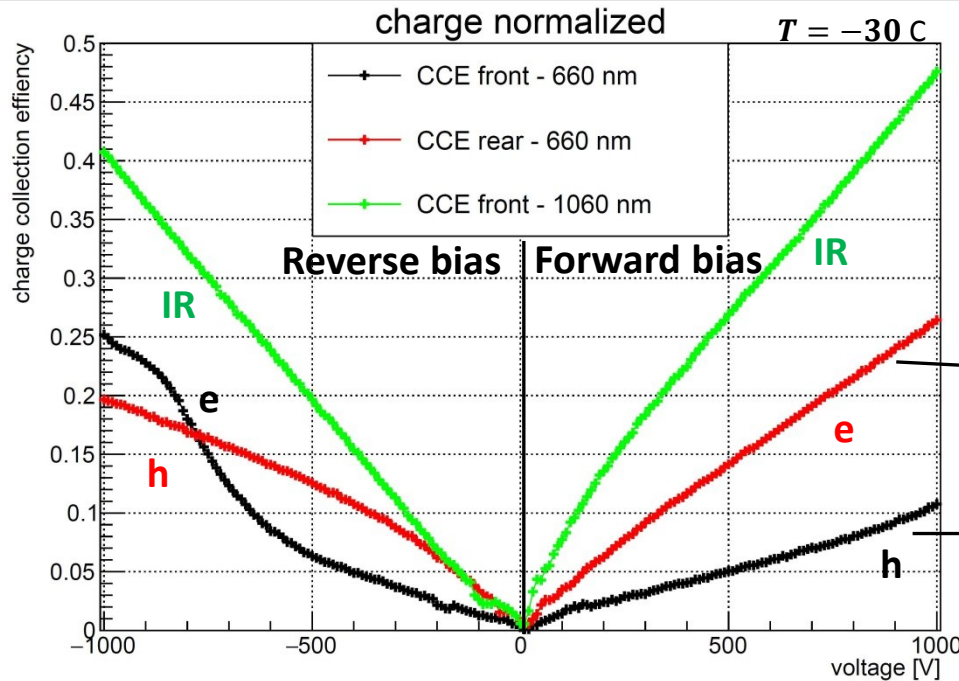


infrared laser
 200 μm sensor
 @ 1000 V and 313 K

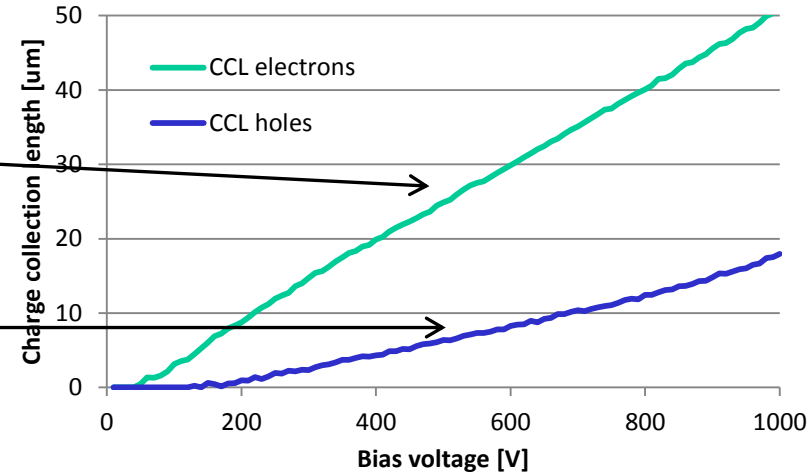
Transfer function of the read-out circuit

$$\rightarrow g = \mathcal{F}^{-1} \left\{ \frac{\mathcal{F}\{measurement\}}{\mathcal{F}\{simulation\}} \right\}$$

The charge collection length



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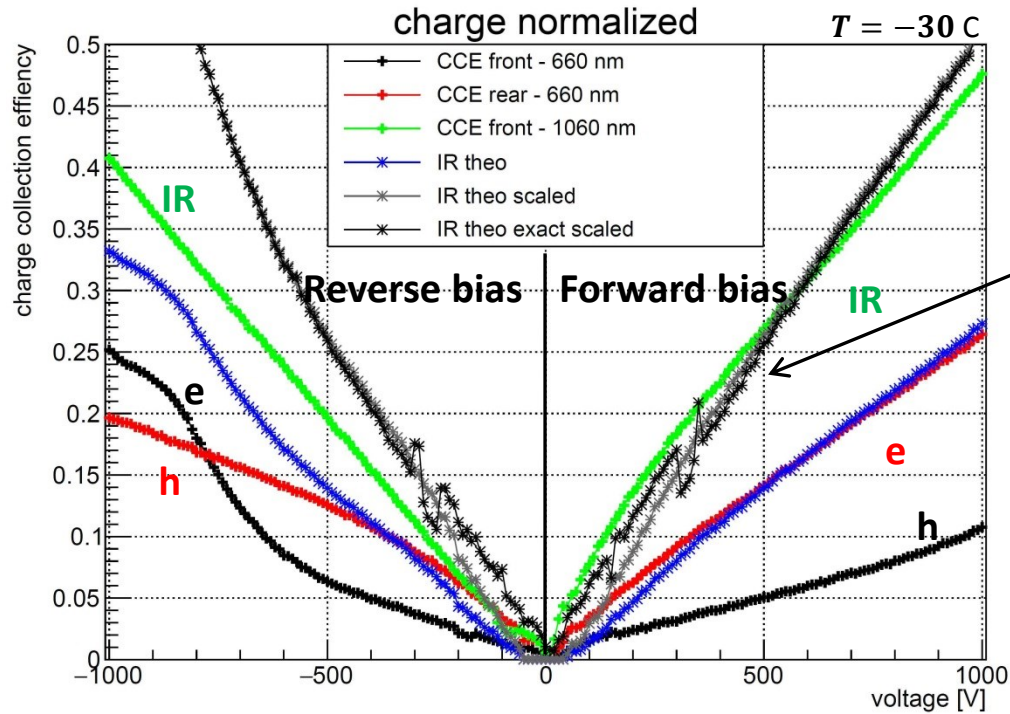
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Charge collection in forward bias



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200 μm HPK p-in-n
 $1.3 \times 10^{16} \text{ p/cm}^2$

$$\frac{\lambda_e \lambda_\gamma \left(\left(1 - e^{-\frac{d}{\lambda_e}} \right) \lambda_e + \left(-1 + e^{-\frac{d}{\lambda_\gamma}} \right) \lambda_\gamma \right)}{\lambda_e - \lambda_\gamma} + \lambda_h \lambda_\gamma \left(1 - e^{-\frac{d}{\lambda_\gamma}} + \frac{-1 + e^{-d \left(\frac{1}{\lambda_h} + \frac{1}{\lambda_\gamma} \right)}}{\lambda_h + \lambda_\gamma} \right) \lambda_h$$

$$d \left(1 - e^{-\frac{d}{\lambda_\gamma}} \right) \lambda_\gamma$$

Use correct term for CCE:

Improvement for low + high bias but not yet stable